



Novel laser-engineered surfaces for electron cloud mitigation

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FUNCTIONAL MATERIALS for OPTICAL & PARTICLE BEAMS Manufacturing with Light

Collaborators:

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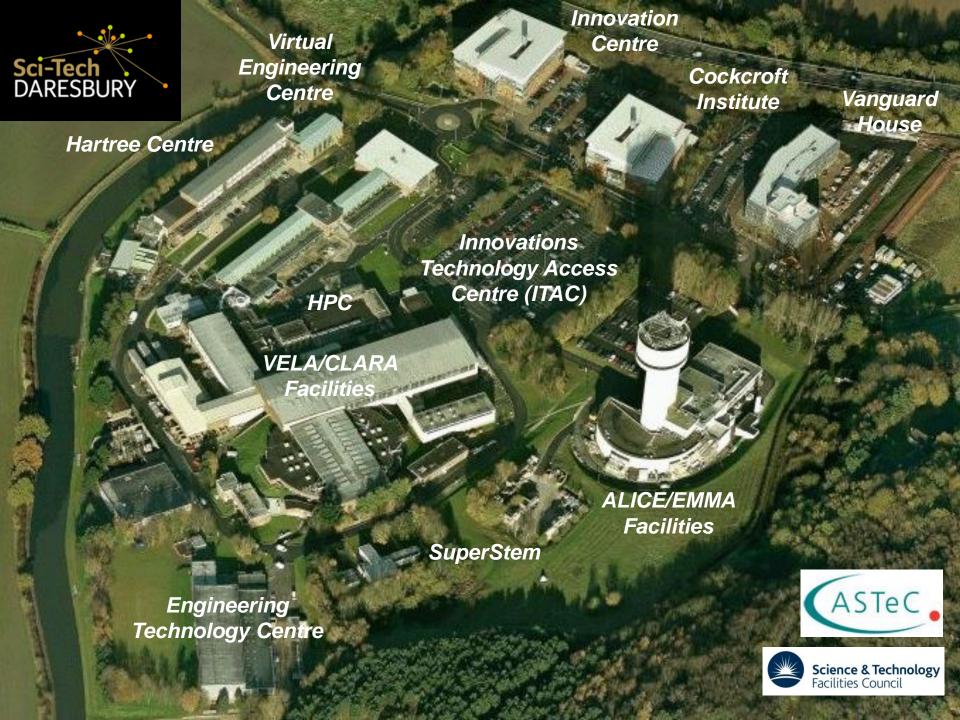
Materials & Photonics Systems (MAPS) Group



- 1) Fabrication & processing of novel functional materials
- (2) Laser functionalisation of traditional materials
- 3 Complex photonics

IMPACT & POTENTIAL APPLICATIONS: storage of information, sensing, circuitry & security, energy sector, particle accelerators, healthcare & creative industries fundamental optical studies, beam shaping, laser technology.

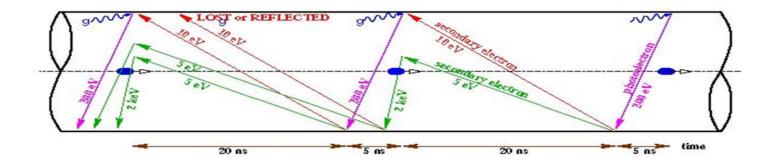




STFC Daresbury Laboratory

- ASTeC Vacuum Science Group
 - SEY measurement and surface analysis facility
 - Electron stimulated desorption
 - RF impedance measurement facility
 - Expertise in e-cloud mitigation in particle accelerators
 - Design of particle accelerator vacuum systems
- STFC grant for Proof of Concept work (2014)

Basic aim of our studies



- 1. Mitigation of beam-induced electron multipacting and electron cloud build-up in a particle accelerator beam chamber due to photo- and secondary electron emission
- 2. Reduction in beam instability, beam losses and emittance growth, & reduction in beam lifetime or heat loads on cryogenic vacuum chambers
- 3. Multipactor mitigation in RF wave guides and space-related high power RF hardware.
- 4. Reducing PEY and SEY in other instruments and devices, where necessary

Standard Objective Reduce The Secondary Electron Yield (e.g. δ_{max} < 1.3 for CERN SPS):

- by Changing surface Chemistry (deposition of lower SEY material)
- by Engineering the surface roughness
- by a Mixture of the above

By active means:

- Weak solenoid field (10 20G) along the vacuum chamber
- Biased clearing electrodes
- Charged particle beam train parameters
 - Bunch charge and sizes
 - Distance between bunches

Advantages:

- Solenoids can be installed on existing facilities (if there is space for them)
- Beam parameters have some flexibility

Disadvantages:

- Requires:
 - controllers
 - power supplies
 - cables
 - vacuum-compatible feedthroughs

i.e. should be avoided if possible

By passive means:

- Low SEY material
- Low SEY coating
- Grooved surfaces
- Special shapes of vacuum chambers
 - an antechamber allows reducing PEY

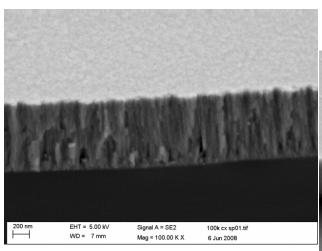
Advantages:

 No Controllers, no power supplies, no cables

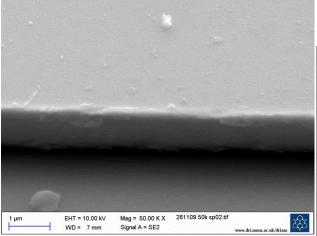
Disadvantages:

- in-vacuum deposition
- difficult to apply on existing facilities
- inconvenient & expensive chamber modifications

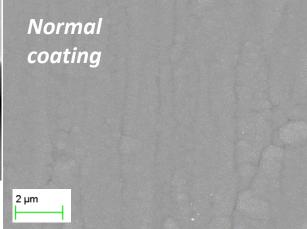
1. Coating with Low SEY Material



Ti-Zr-V-Hf

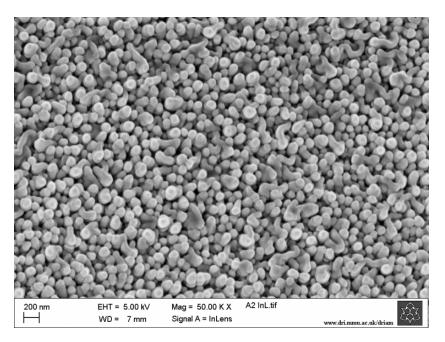


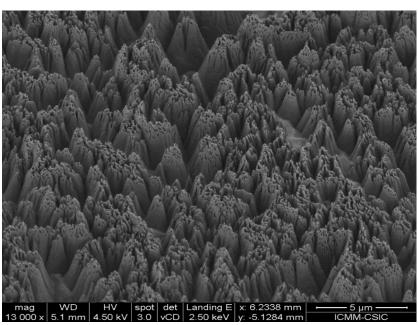
Ti-Zr-Hf-V-N



a-C at CERN

2. Coating with a low SEY material with sub-micron size structure



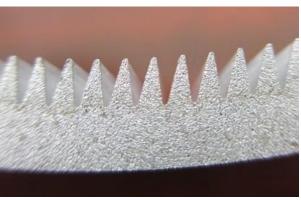


Ti-Zr-V black

Ag plating, ion etched with Mo Mask I. Montero et. al, Proc. e-Cloud12

3. Modifying the surface geometry making mechanical grooves



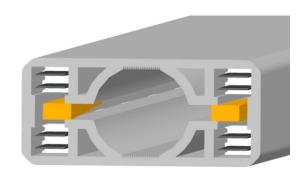


 $\frac{\mathsf{w}}{\mathsf{b}}$

KEKB vacuum chamber (by courtesy of Y. Suetsugu)

By A. Krasnov and by L Wang et.al

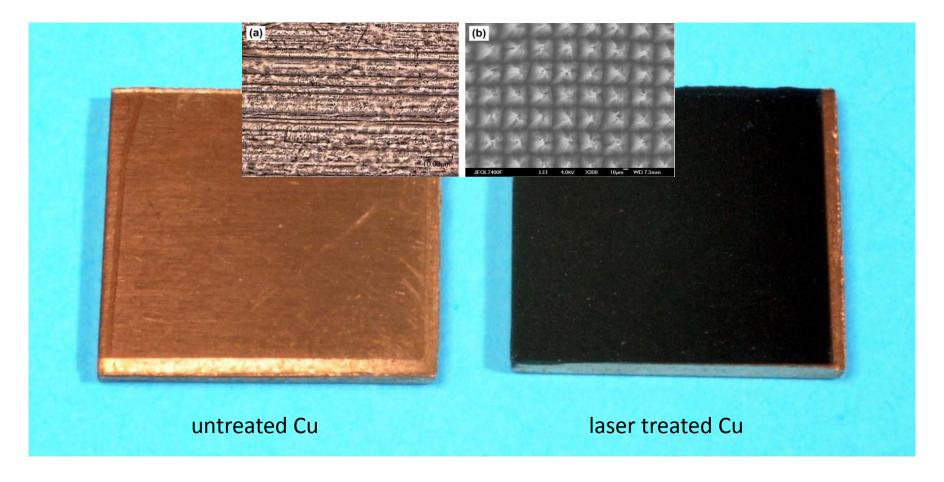
4. Modifying the vacuum chamber geometry making an antechamber



ILC wiggler vacuum chamber

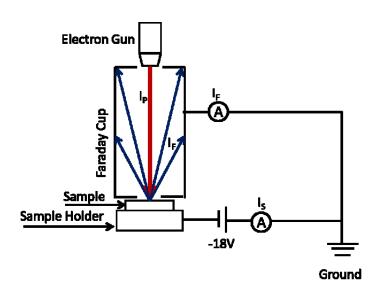
Introducing new technology

• Laser treatment of metal surfaces in air or noble gas atmosphere



- beam is raster-scanned in both horizontal and vertical directions
- with average laser energy fluence just above ablation threshold of the metal
 - We call these "Laser-engineered surface structures" (LESS)

SEY Measurements at STFC Daresbury Laboratory



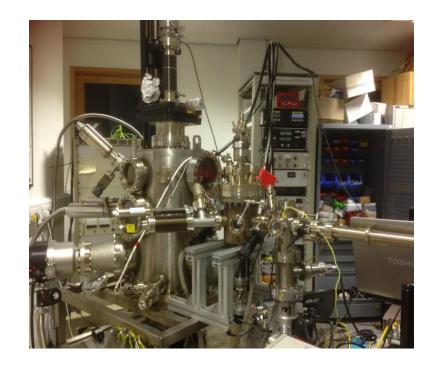
Define the secondary electron yield, SEY or δ , in the usual way

$$\delta = \frac{I_F}{I_P} = \frac{I_F}{I_F + I_S}$$

 I_P is the primary beam current

 I_F is the secondary electron current, including elastic and inelastic processes, measured on the Faraday cup

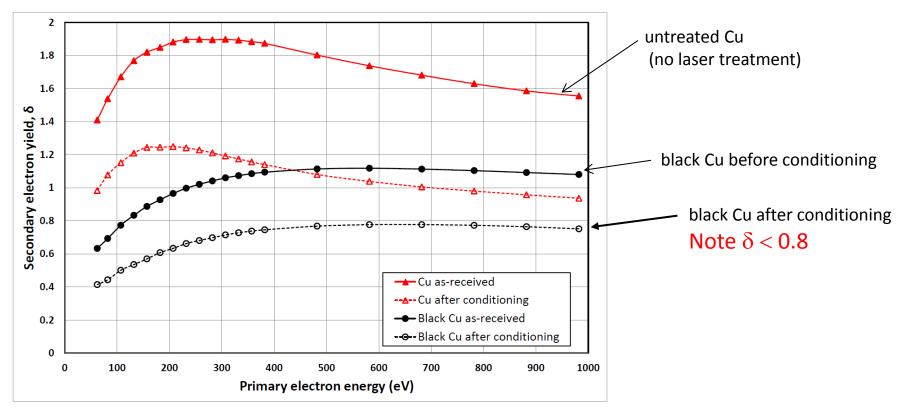
 $I_{\rm s}$ is the current on the sample



Analysis chamber with:

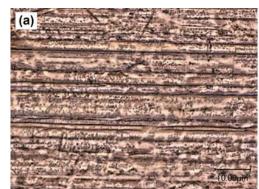
- XPS,
- Flood e-gun (0.5 2.0 keV)
- Sample heater
- Ar ion beam

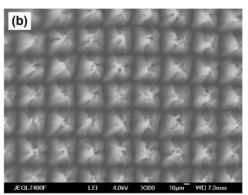
RESULTS: SEY of Cu as a function of incident electron energy



Original Data
June 2014

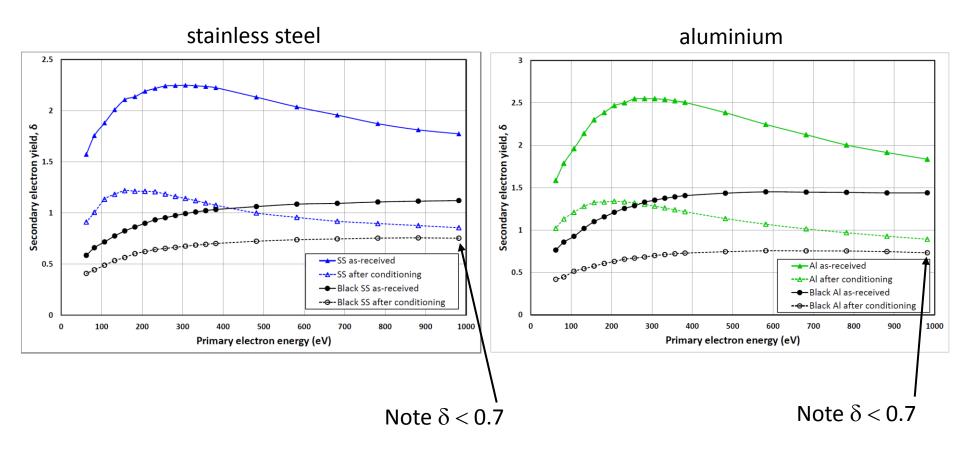
We have complete control over the highly regular surface topography





High-resolution SEM images of the Cu samples: (a) untreated and (b) laser treated

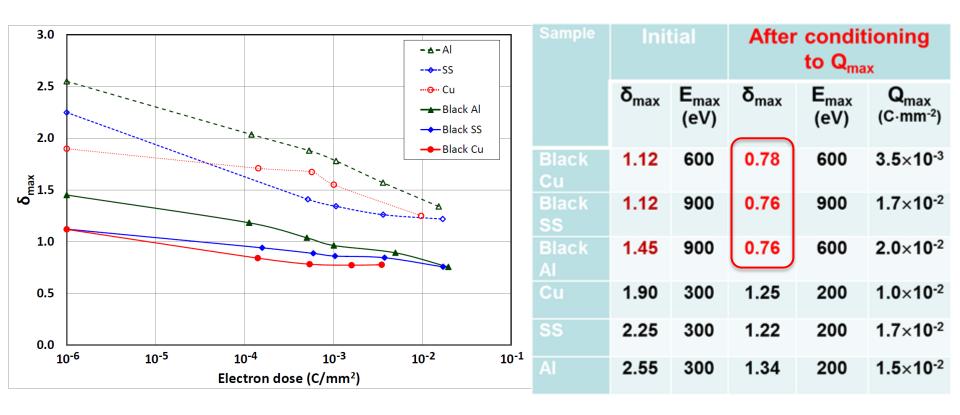
RESULTS: SEY of SS & Al as a function of incident electron energy



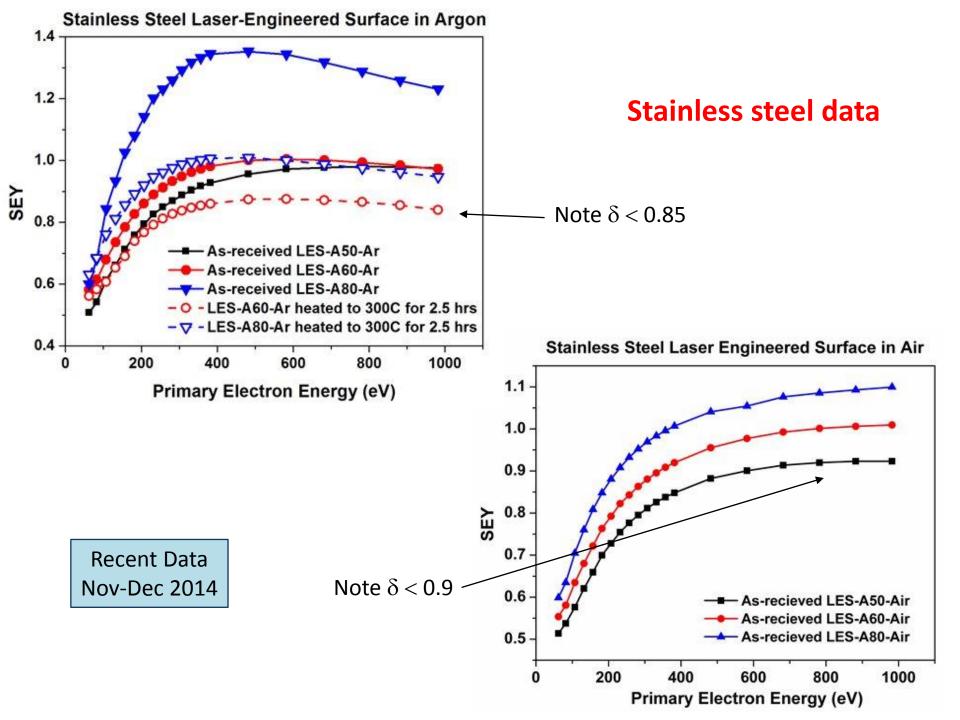
Applied Physics Letters 12/2014; 105(23): 231605

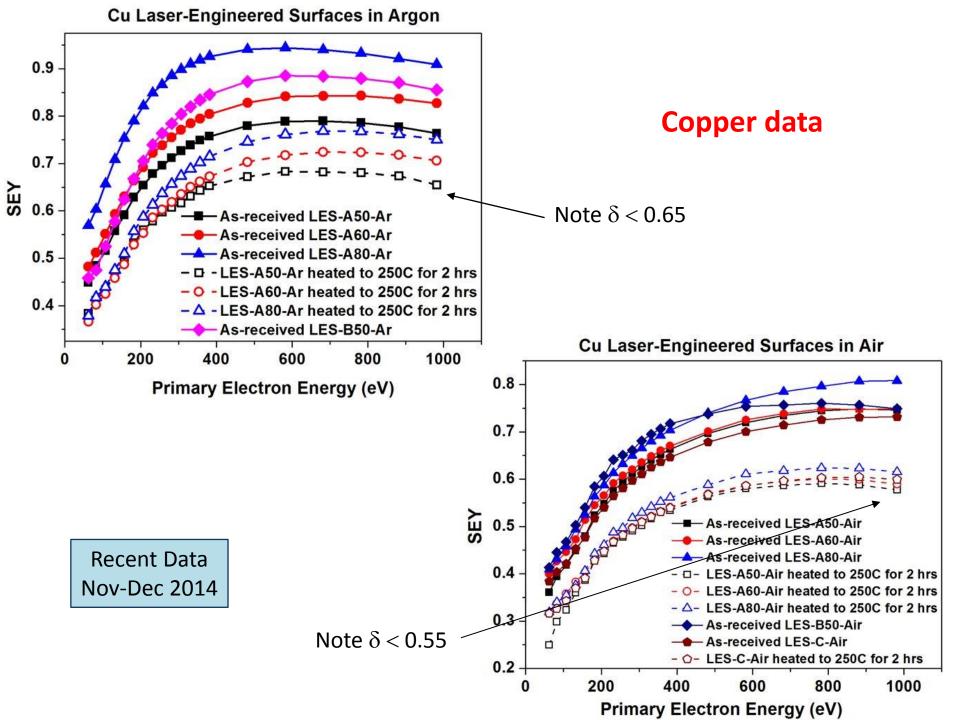
Original Data June 2014

δ_{max} as a function of electron dose for Al, 306L SS and Cu



Reduction of δ_{max} after conditioning is attributed to change in surface chemistry due to electron-beam induced transformation of CuO to sub-stoichiometric oxide, and build-up of a thin graphite C-C bonding layer on the surface. Verified by XPS results.



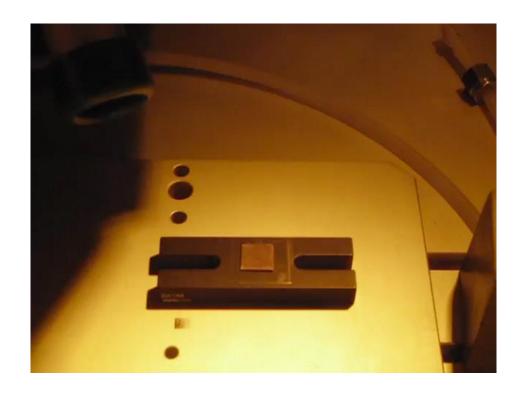


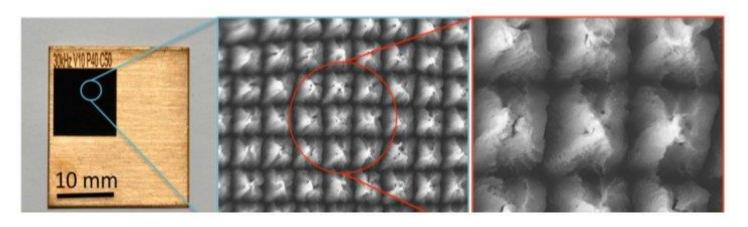
How do we do this?

Laser processing of Copper

beam is raster-scanned in both horizontal and vertical directions

with average laser energy fluence just above ablation threshold of the metal

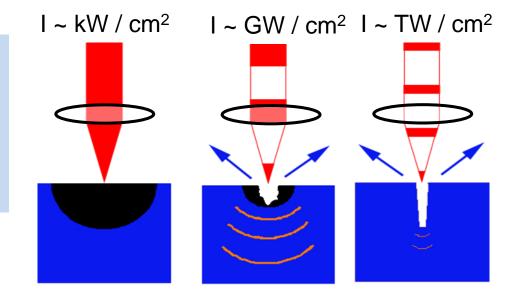




Appl. Phys. Lett. 101, 2319021 (2012). Physics Highlights – Physics Today (February 2013). Opt. Mater. Exp. 1,1425 (2011).

Laser Ablation of Metals - Components of light control

- Laser Wavelength
- Energy & Power
- Spot size & shape of beam
- Pulse length

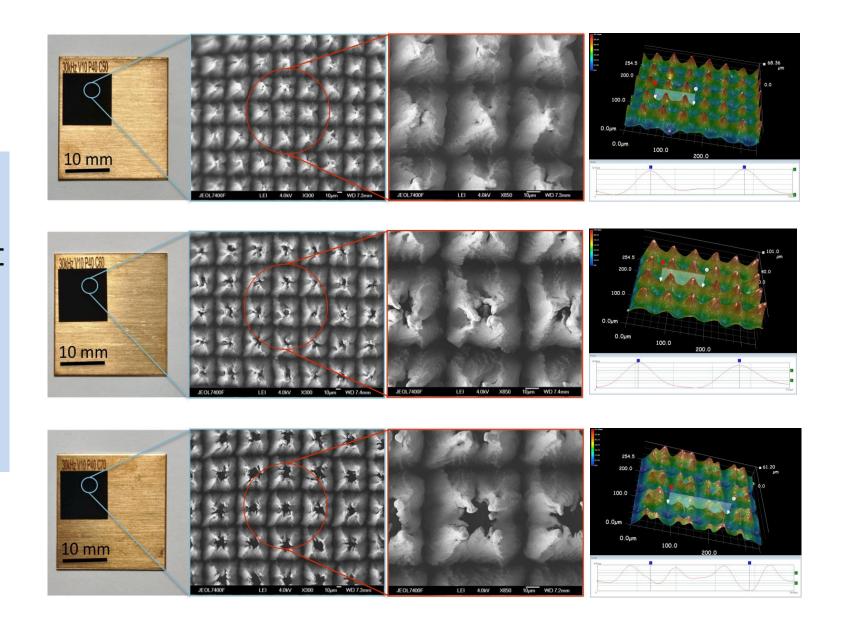


Part of this **ENERGY** (once randomised) is

- a) Conducted into the bulk of the material
- b) Converted into directed kinetic energy by thermal expansion of the heated layer.

TWO distinguished regimes are identifiable at high irradiances:

- 1. Short (ns) pulses: Dominated by the expansion and ablation of material;
- **2.** Ultra-short (ps & fs) pulses: Dominated by heat conduction, as hydrodynamic motion during the pulse duration is negligible.



Appl. Phys. Lett. 101, 2319021 (2012). Physics Highlights – Physics Today (February 2013). Opt. Mater. Exp. 1,1425 (2011).

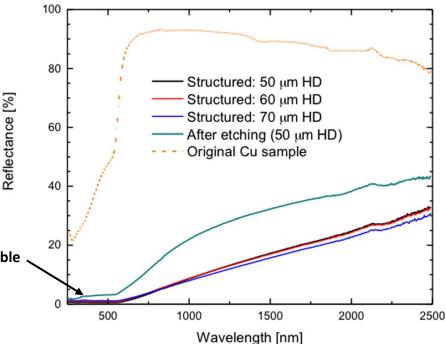
Metals treated so far Copper; Aluminium; Titanium; S.Steel

25 mm

A practical example:

Laser micro-structured copper mirror (optical / THz separator)

Fabricated for the Beam Diagnostics Group at ASTeC, Daresbury Laboratory.



Reflectance of "black copper"

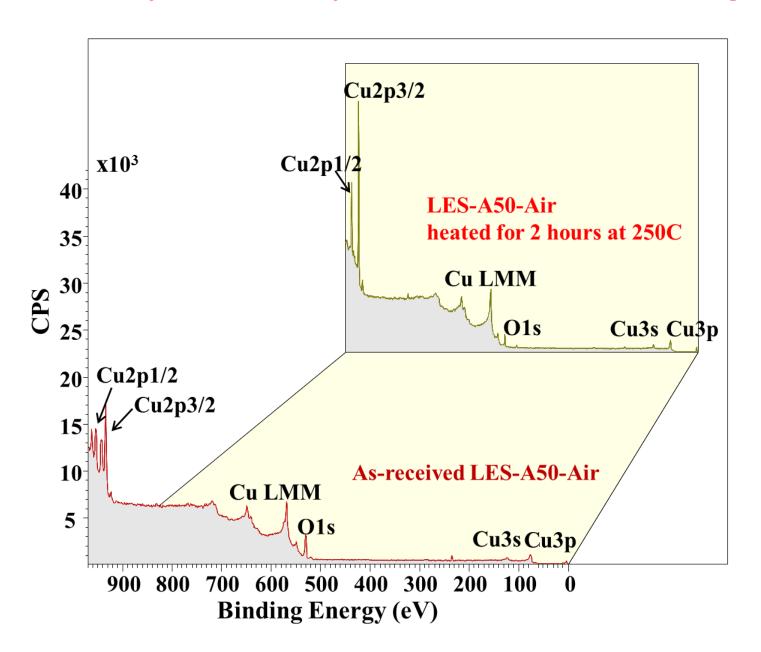
< 3% across visible

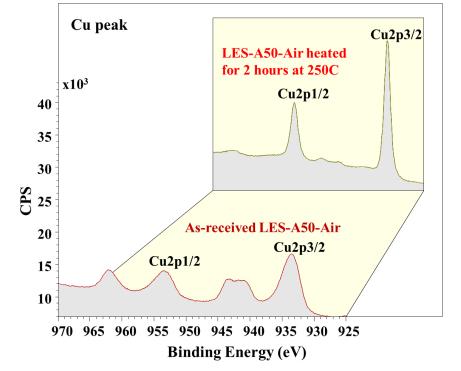
Appl. Phys. Lett. 101, 2319021 (2012).

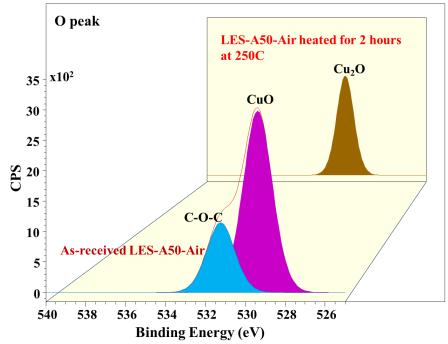
Opt. Mater. Exp. 1,1425 (2011).

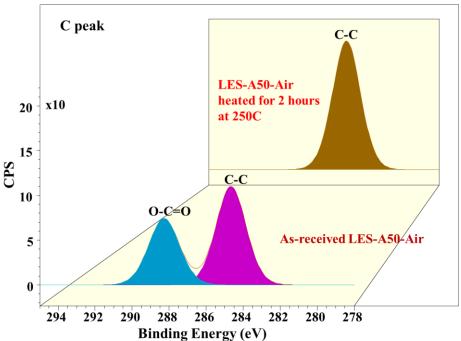
Int. J. Adv. Manu. Technol. 66, 1769 (2013).

XPS analysis of Cu sample before & after conditioning



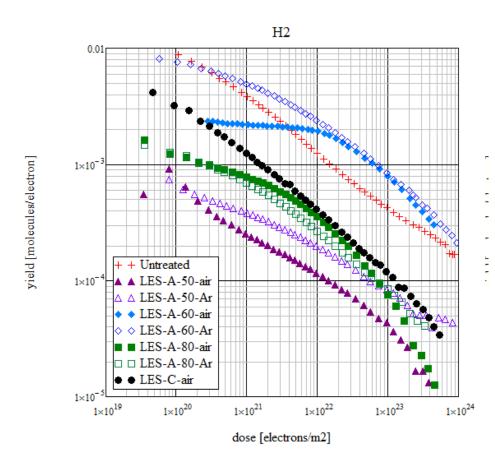






Electron Stimulated Desorption (ESD)

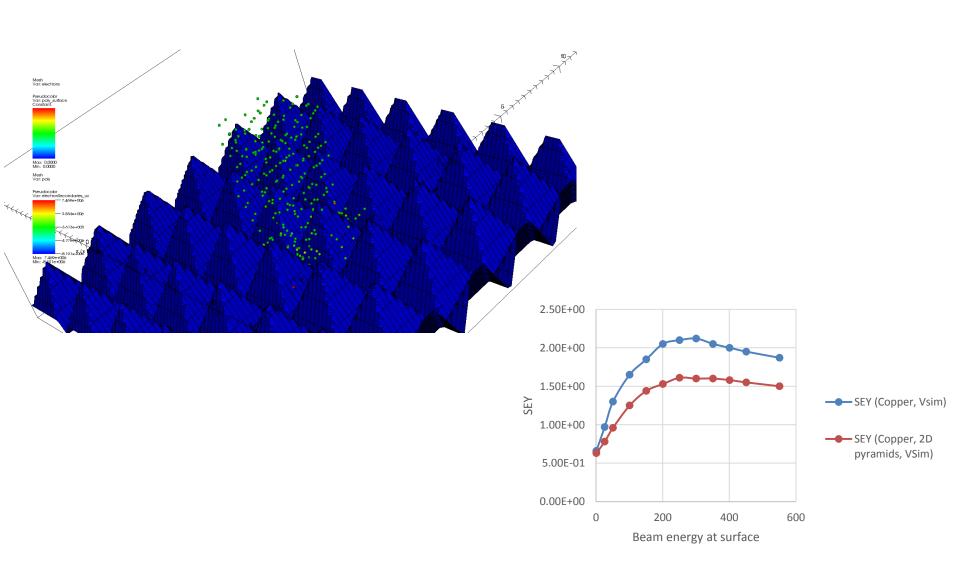
- 9 samples were tested:
 - Cu blank gaskets ∅48 mm
 - Untreated (2 samples)
 - LES-A type treated in air or Ar atmosphere
 - LES-C type treated in air
 - $E_{e} = 500 \text{ eV}$



- Main results:
 - LES-A-50, LES-A-50 and LES-C demonstrated lower ESD yields than untreated samples
 - LES-A-50 treated in air yielded the best results

Simulations

Very preliminary studies of e-cloud mitigation being carried out (in VSim) by Jonathan Smith of Tech-X Corporation in the UK



Summary

- ❖ Laser conditioning of metal surfaces is a very viable solution for reducing the SEY < 0.6
- Even the initial (unconditioned) SEY of 1.1 for black SS is low enough to suppress e-cloud in, e.g., the SPS, LHC or HL-LHC.
- The technique can easily be applied to existing vacuum surfaces where the improvement has to be done *in-situ* with minimum disturbance to the beam line.
- The blackening process can be carried out in air at atmospheric pressure; the actual cost of the mitigation is therefore considerably lower, a fraction of existing mitigation processes. The process is also readily scalable to large areas.
- ❖ The surface is highly reproducible and offers a very stable surface chemistry which can be influenced during the process. The surface is robust and is immune to any surface delamination which can be a detrimental problem for thin-film coatings.
- ❖ The treated surface remains the same material, therefore it is unlikely to have a significant effect on the surface impedance recent measurements verify this.





Thank you for your attention

nanosecond processing of Al

Material: Anodised aluminium

Wavelength: 1064 nm

Pulse length: 10 ns

Focal spot diameter: 60 µm

Processing speed: 1200 mm/s

